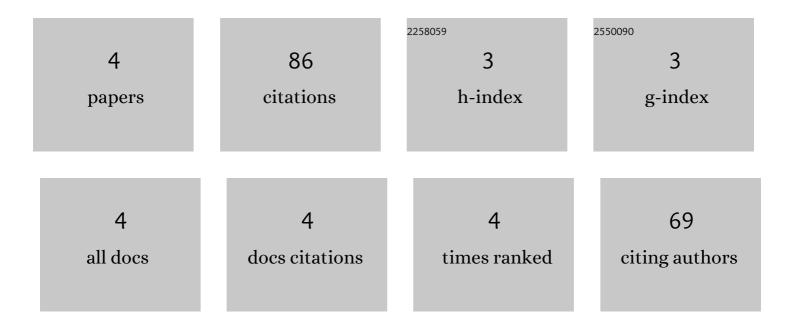
Henry Herbol

List of Publications by Year in descending order

Source: https://exaly.com/author-pdf/12079226/publications.pdf Version: 2024-02-01



#	Article	IF	CITATIONS
1	Secondary Electrons in EUV Lithography. Journal of Photopolymer Science and Technology = [Fotoporima Konwakai Shi], 2013, 26, 625-634.	0.3	53
2	Electron Penetration Depths in EUV Photoresists. Journal of Photopolymer Science and Technology = [Fotoporima Konwakai Shi], 2014, 27, 611-615.	0.3	13
3	Studying secondary electron behavior in EUV resists using experimentation and modeling. , 2015, , .		13
4	Studying thickness loss in extreme ultraviolet resists due to electron beam exposure using experiment and modeling. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2015, 14, 043502.	0.9	7